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Technology Center 2600

			Sheet <u>1</u> of <u>1</u>		
FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE	ATTORNEY DOCKET NO.	APPLICATION NO.		
	PATENT AND TRADEMARK OFFICE	392.1680	09/546,214		
		FIRST NAMED INVENTOR			
LIST OF REFER	ENCES CITED BY APPLICANT	Atsushi WATANABE et al.			
4.4		FILING DATE	GROUP ART UNIT		
(Use s	everal sheets if necessary)	April 10, 2000	2721		

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	!	DOCUMENT NO.	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
4	AA	5,845,048	12/01/98	Masumoto			
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FOREIGN PATENT DOCUMENTS

1		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSL YES	ATION NO
Sh	AB	2 085 629	04/28/82	United Kingdom				

OTHER R	EFERE	NCES (Including Author, Title, Date, Pertinent Pages, Etc.)	TRANSL YES	ATION NO
St.	AC	Ichiro Masaki, "Industrial Vision Systems Based on Application-Specific IC Chips", IEICE Transactions, Institute of Electronics, Vol. E74 No. 6, June 1, 1991, pages 1728-1734		
	AD	Michael Magee et al, "An Industrial Model Based Computer Vision System", Journal of Manufacturing Systems, Society of Manufacturing Engineers, Vol. 14 No. 3, 1995, pages 169-186		
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EXAMINER /	DATE CONSIDERED
Heorgh As	4-22-04
*EXAMINER: Initial if reference considered, whether	or not citation is in conformance with MPEP 609. Draw line through

citation if not in conformance and not considered. Include copy of this form with next communication to applicant.